CMOS sensors with high resistivity epitaxial layer

State of the art STAR – Ultimate sensor ALICE/ CBM ILC / AIDA / superB Integration, Plume project Summary and outlook

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CMOS pixel sensor : State of the art

- Main application
 - Foreseen to equip vertex detectors
- Main features / Principle of operation
 - MIMOSA serie: manufactured in 0.35 µm OPTO process
 - Thermal diffusion of electrons in a thin epitaxial layer (10-20 μm)
 - ➢ Signal ~ 1000 e-
 - > Low material budget (thinned down to 50 μ m)
 - Charge collection shared between N-Well diodes
 - High granularity (10-40 μm pitch)
 - > Excellent (micronic) spatial resolution
 - Signal sensing and analog processing in pixel (preamp, CDS, etc.)
 - Signal processing µ-circuits integrated on sensor substrate
 - ADC/digital output, Zero suppression circuitry integrated in chip periphery
 - Read-out in rolling shutter mode (columns read out in //) read out time = typically 200 ns per row
 - Impact on downstream electronics (cost)

Priority given to high granularity, low material budget, low power consumption, with sufficient read-out speed and radiation tolerance.





Ultimate Sensor for STAR Vertex detector (1)

• STAR PIXL upgrade (physics run in 2014)

Requirements

- \succ ~ 150 kRad and few 10¹² n_{eq}/cm²/year
- Temperature 30-35 °C (air flow cooling only)
- Power consumption ~130 mW/cm²
- \succ Spatial resolution < 10 μ m
- > Integration time ~< 200 μ s to cope with occupancy
- (~200 hits / 4 cm² sensor / read-out cycle)
- Design
 - > 2 layers (2.5/8 cm radius)
 - \succ 40 ladders: 50 μ m silicon, Flex kapton / aluminium cable
 - > 10 Mimosa chips/ladder \Rightarrow 370 x 10⁶ pixels
 - > 0.37% X₀ per layer
- Ultimate (alias Mimosa 28)
 - Final sensor for the upgrade of STAR pixel layers of the vertex detector
 - \succ Design process Austria Micro System AMS-0.35 μm OPTO, 4 metal-and 2 poly- layers
 - > 15 µm thick epi. layer, High-Resistivity substrate (400 Ohm.cm)
 - Radiation tolerant structures
 - > 928 (rows) x 960 (columns) pixels, 20.7 µm pitch \Rightarrow ~20 x 23 mm²
 - Fast binary readout, zero suppression
 - > 200 µs read-out time: Suited for 10⁶ part/cm²/s

Chip delivered in spring 2011 First data taking in 2013 First vertex detector equipped with CMOS pixel sensors !

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50 μm thinned silicon ladder on a flex kapton / aluminium cable





STAR – Ultimate (2) : Performances

- Test Beam @ CERN-SPS (July 2011), 120 GeV pion beam
 - Goal: approach STAR running conditions
 - ≻ T = 30 °C
 - Chip irradiated @ 150 kRad
 - Read-out time = 198 μs
- Results
 - Efficiency \geq ~99.9% with a ~<10⁻⁶ fake rate
 - Spatial resolution ~ 3.7 μ m
 - Uniformity checked
- Under study / to be done
 - Fluence of > 3x10¹² n_{eq}/cm² (already tested with previous prototype M26)
 - Large incident angle







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CBM / ALICE : towards 0.18 μm fabrication process

- CBM: Cold Baryonic Matter experiment @ FAIR
 - Micro-Vertex Detector made of 2 stations
 - Double sided stations
 - \blacktriangleright ~≤ 0.5% X₀ per station
 - Intermediate prototype in ~2016
 - Running conditions (ultimately in ~2020)
 - > Operation in vacuum @ negative temp.
 - \blacktriangleright r.o. time ~≤ 10 µs; > 10¹⁴ n_{eq}/cm²; ≥~ 30 MRad
 - ALICE: ITS upgrade (~ 2016 LHC shutdown)
 - Different options:
 - hybrid pixels / CMOS sensors
 - Introducing a layer L0 ~ 25 mm radius
 - Potentially replace part of the ITS
 - Requirements
 - > 2 x $10^{13} n_{eq}/cm^2$; > 2 MRad ; @ 30 °C
 - Upgraded sensors
 - 0.18 μ m triple-well High Res. fabrication process
 - Presumably double sided read-out
 - Possibly double sided ladders (see PLUME)
 - Possibly large area sensors

Hi. Res./0.18 μ m \Rightarrow Extend application domains





ILD - AIDA - SuperB

- AIDA (EU-FP7 WP9.3) test beam infrastructure (2014)
 - Large area beam tel. (~6x4 cm²)
 - Alignment Investigation Device (AID)
 - > Reproduce a VTX detector sector
 - Double sided ladders mounted on precise adjustable stages
 - Thermo-mechanical studies
- SuperB (≥~2016)
 - ~ 100 Mpart/cm²/s @ 1.5 cm radius (safety factor of 5)
 - Baseline: Babar VTX + boost/2. \Rightarrow $\Delta t/2$ ~ needs to improve $\sigma_{\rm IP}$
 - 1st option add a layer zero with striplets (1.8cm)
 - Upgrade: CMOS sensors or Hybrid pixel
 - > Charge collection optimisation (chip by V.Re et al., INFN Pavia/ Bergamo)
- ILD for International Linear Collider
 - Detector Baseline Document (2012)
 - Inner layers
 - > Optimize r.o. speed and spatial resolution
 - $\succ~16x16/80~\mu m^2$ pitch, 10/40 μs r.o. time
 - \geq 3/5 μ m sp. resolution
 - Outer layers
 - Optimize Power dissipation
 - $\succ\,$ 4bits ADC, 35 μm pitch, 100 μs r.o. time
 - 2 demonstrator prototypes being designed (2011)

Study/demonstrate full potential of double sided ladders

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First 3-plane









Integration – Plume - Serwiete (1)

• Plume

- Proof of principle for ILD-VXD concept (DBD 2012)
- Pixelated Ladder with Ultra low Material Embedding
- Double sided ladder
 - > Sensors thinned down to 50 um
 - Silicon carbide foam/support (2mm)
 - Low mass flex cable : electrical services: power, control, data

• 1st prototype (2010)

- Goal: focus on functionnalities
- 1 double sided ladder = 8.4M pixels (12 chips)
- Mat. Budget:
 - 0.8% X0 (average)
 - 0.6% X0 (active area)
- On a module: 12 channels in //.
- 1 ladder produced
 - chips+flex are fully functionnal tested at 80 MHz = 80Mbits/sec
- Air cooling assumed
- Extendable concept in length.

2nd prototype (end 2011)

- Focus on material budget
 - ~ 0.5% X0 (average)
 - ~ 0.3% X0 (active area)
- Narrower flex (mirrored on both side)
 - > Copper replaced by aluminium
- New support (lower mass spacer)







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Integration – Plume - Serwiete (2)

• SERWIETE

- SEnsor Row Wrapped In an Extra Thin Envelop
- Idea (with IMEC comp., CERN)
 - > Sensor mounted on flex and wrapped in polymerised film
 - Reduce bounding material
 - Proto in summer 2011
- Mid term objectives:
 - 2011: mechanical tests
 - > measure vibration sagitta under air flow and operation)
 - Thermal studies
 - Data output path studies
 - > Digital output at ~200 MHz with optic fibers ?
 - Produce 10 ladders for AID box (~2013)
 - Space for improvement:
 - Reduce mat. Budget (SERWIETE)
 - Narrower flex, less bounding material
 - ➢ Increase active area w.r.t. to digital part. (Mimosa26 ⇒ ultimate)
 - Reduce thickness of the support ?
 - AID: 50 M pixels ! (zero supp. + PXI DAQ)



Fully functional microprocessor chip in flexib plastic envelope. Courtesy of Piet De Moo IMEC company, Belgiur



Global material budget under control CMOS sensors will benefit from steady industry progress for integration

Summary

- CMOS sensor technology, initally developped for ILC is mature and extends its domains of applications
 - Great potential when granularity, material budget and power comsumption are the leading constraints.
 - Now used successfully (e.g. EUDET beam telescope)
 - 1st vertex detector (STAR) equipped with CMOS in ~ 2013
- Mid term plans
 - Many projects / options under study
 - > CBM-MVD \geq ~2015 (rad.tol.)
 - ALICE-ITS option: Technical proposal end 2011 ~ 2017 also considered: ALICE-FOCAL, FW tracker
 - > ILD-VTX (Linear Collider) option Det.Baseline.Doc. (double sided ladders, ADC, elongated pixels, etc.)
 - > AIDA (Large sensors, stitching): 2014
 - > R & D for Electron-Ion Collider (eRHIC) (Large sensors for forward disks) ~ 2017
 - > R & D for superB (in pixel FEE, speed) ~ 2017
 - > NA63 (e⁺ source for CLIC)
 - Other domains of application
 - > Hadrontherapy, dosimetry, etc.
- The CMOS technology has not reached its limits yet
 - Higher resistivity \Rightarrow enhance S/N
 - − 0.18 μ m feature size (first proto in 2011) \Rightarrow rad.tol., read-out speed, mat. budget
 - Deep P-well ⇒ S/N
 - Long term: multi-tier (3D) sensor



Back up

MAPS development trend



STAR – Ultimate Preliminary results



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Ionising radiation 12

International Linear Collider (ILC) running conditions

Bunch Train

Bunch Spacing

- $e+e-: \sqrt{s}$ up to 1 TeV
- 5 trains/s
- 2680 bunches/train
- 337 ns between bunches
- Occupancy governed by beam background (beamstrahlung)

Physics goals & running conditions

- single point resolution $\sim 3 \mu m$
- material budget ~0.2% X₀/layer
- integration time 25 100µs
- radiation tolerance > 300Rad, few 10¹¹n_{eq}/cm²
- P < 0.1 2 W/cm²

σ _{ιP} = a ⊕ b/psin^{3/2}θ a = 5μm, b = 10μm GeV



~1 ms

0.2 s

369 ns

CMOS sensor-based Vertex detector for ILD



layer	ra dius (mm)	length (mm)	# ladders	# sensors*	#.10 ⁶ pixels	t _{int} (μs)	σ _{s.p.} (μm)
1	16/18	125	14	168	66 + 16	40 / 10	< 3 / ~5
2	37/39	250	26	312	2x112	100	< 4
3	58/60	250	40	480	2x173	100	< 4
total			80	960	652		

* Numbers corresponding to current CMOS technology (0.35 μm) prototypes

ILD

CMOS sensors for the ILD-VTX

• Two types of sensors :

* Inner layers ($\lesssim 300 \text{ cm}^2$) : priority to read-out speed & spatial resolution \hookrightarrow small pixels (16×16 / 80 μm^2) with binary charge encoding

 \hookrightarrow t_{r.o.} \sim 50 / 10 μs ; $\sigma_{sp} \lesssim$ 3 / 5 μm

- st Outer layers (\sim 3000 cm 2) : priority to power consumption and good resolution
 - $\,\,\hookrightarrow\,\,$ large pixels (35imes35 μm^2) with 3-4 bits charge encoding

 $\hookrightarrow {
m t}_{r.o.} \sim$ 100 $\mu s; ~\sigma_{sp} \lesssim$ 4 μm

- 2-sided ladder concept for inner layer (see W.Dulinski's talk) :
 - * square pixels (16×16 μm^2) on internal ladder face (σ_{sp} < 3 μm) & elongated pixels (16×80 μm^2) on external ladder face (t_{r.o.} ~ 10 μs)
- Sensor prototyping : design under way
 - * MIMOSA-30: inner layer prototype with 2-sided read-out
 - \hookrightarrow one side : 256 pixels (16×16 μm^2)
 - other side : 64 pixels (16imes64 μm^2)
 - * MIMOSA-31: outer layer prototype
 - \hookrightarrow 48 col. of 64 pixels (35imes35 μm^2) with 4-bit ADC







Spatial resolution examples



EUDET telescope

- Beam telescope of the FP6 project EUDET
 - * 2 arms of 3 planes (plus 1-2 high resolution planes)
 - * MIMOSA-26 thinned to 50 μm
 - $*~\sigma_{extrapol.} \sim$ 1-2 μm EVEN with e $^-$ (3 GeV, DESY)
 - ☆ frame read-out frequency O(10⁴) Hz
 - * running since '07 (demonstrator: analog outputs) at CERN-SPS & DESY (numerous users)



From low to High resistivity

• High resistivity ⇒ larger depleted region ⇒enhance S/N



Fast and more efficient charge collection → should be radiation tolerant

SERWIETE SEnsor Raw Wrapped In an Extra-Thin Enveloppe (HP2, EU-FP7)

Goals :

- to achieve a sensor assembly mounted on flex and wrapped in polymerised film with <0.15 % X₀ for 1 unsupported layer (sensors – flex cable – film)
- to evaluate the possibility of mounting supportless ladder on cylindrical surface like beam pipe (used as mechanical support). Proof of principle expected in 2012

Working program :

- prototype Nr. 1 (2010) made of 1 analog sensor : MIMOSA-18 (analog output, ~4 ms @16MHz)
- prototype Nr. 2 (2011) made of 3 digital sensors : MIMOSA-26 (binary output, $\sim 100 \ \mu s \ @80MHz$)

prototype Nr. 1 : April 2010



Fully functional microprocessor chip in flexib plastic envelope. Courtesy of Piet De Moo IMEC company, Belgiur

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prototype Nr. 2 : summer 2011

Context of development :

- Collaboration with IK-Frankfurt and GSI/Darmstadt (CBM coll.) within HP2 project (WP26)
- Synergy with Vertex Detector R&D for CBM, ALICE (?) etc.

Power dissipation and power pulsing (ILC example)

Pulsing strategy

- x Activity period ~ 2 to 4 ms over the 200 ms train
 - ➔ Estimated duty cycle range: 1/50 to 1/100
- **x** For stability reasons, not all element switchable
 - ➔ Test started for the analog part
 - ➔ To be done for the digital circuitry



Assuming: 0.18µm techno. & 1.8 V voltage & continuous operation		sensor		2-sided ladder			whole detector			
		switch.	not-swi.	total	switch.	not-swi.	total	switch.	not-swi.	total
inner layer	power (W)	1,575	0,025	1,6	18,9	0,3	19,2	699 W	12 W	700 W
	current (A)	0,875	0,014	0,89	10,5	0,17	10,67	000 W	IZ VV	/00 ₩
outer Layers	power (W)	0,490	0,010	0,5	5,88	0,12	6	382 A	7 A	390 A
	current (A)	0,272	0,006	0,28	3,27	0,07	3,33			

Average power (integrating pulsing) 20 to 30 W

→ Air cooling probably good enough

Elongated pixels and large pitch

- Large pitch : Motivations
 - st trackers require $\sigma_{sp}\gtrsim$ 10 μm st calorimeters require O(100 imes 100) μm^2 cells
 - ⇒ minimise number of pixels for the sake of power dissipation, integration time and data flow
- Large pitch : Limitations
 - * DANGER: increasing distance inbetween neighbouring diodes
 - ⇒ particles traversing sensor "far" from sensing diodes may not be detected because of e⁻ recombination
 - * "fragile" detection efficiency, exposed to losses due to irradiation, high temperature operation & slow read-out
- Elongated pixels : Test results
 - * elongated pixels allow minimising the drawbacks of large pitch
 - * concept evaluated with MIMOSA-22AHR prototype, composed of a sub-array with 18.4×73.6 μm^2 pixels $\triangleright \triangleright \triangleright$
 - * m.i.p. detection performances assessed at CERN-SPS (T \sim 15°C)
 - $-\!\circ~\epsilon_{det}\sim$ 99.8 %
 - $-\circ~\sigma_{sp}\sim$ 5-6 μm (binary charge encoding)
- Square pixels : prototype under fabrication
 - * MIMOSA-29 being fabricated on high-res epitaxy
 - st pixels of \leq 80imes80 μm^2



Ultimate

- Process Austria Micro System AMS-C35B4/OPTO uses 4 metal- and 2 polylayers.
- The thickness of the epitaxial layer stretches out up to 15 µm in Hi-Resistivity substrate (400 Ohm.cm)
- Full reticle 960 x 928 pixel matrix
 - Longer integration time $\sim 200 \ \mu s$
- size of the chip of 20.22 mm x 22.71 mm
- Temperature 30-35 °C
- Power consumption ~100 mW/cm²
- Space resolution < 10 µm
- 150 kRad / yr & few 10¹² Neq /cm² /yr

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Luminosity = 8 \times 1027 / \text{cm}^2 / \text{s} at RHIC_II
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~200-300 (600) hits / sensor (~4 cm2) in the integration time window Shot integration time ~< 200 µs



Future techniques: stitching ("one die per wafer")



Maximum length of monolithic ladder (8' wafer): 10-15 cm

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ULTIMATE Design & Optimisation (1)

Reduction of power dissipation:

- Solution Soluti Solution Solution Solution Solution Solution Solution S
- Solution of pixel pitch v.s. non ionising radiation tolerance
 - Larger pitch: 18.4 μm → 20.7 μm
 - \Box Shorter integration time: 185.6 µs
 - ➔ Validated by a small prototype
- Optimisation of power consumption of some blocks
- → Estimated power consumption ~130 mW/cm²

Pixel improvement: charge collection, radiation tolerance

- Search High resistivity EPI substrate & radiation tolerance design
 - Lab test with ⁵⁵Fe at 35 °C and integration time imposed by the STAR requirements shows:
 - Conversion gain is improved by a factor of two
 - □ ENC >~ 10 e⁻ before irradiation
 - \Box ENC >~ 13 e⁻ after irradiation with 150 kRad
 - \Box ENC >~ 16 e⁻ after irradiation with 3 x 10¹² Neq/cm²
 - SNR up to 30 after irradiation
 SNR ~30 for standard resistivity EPI before irradiation
 - Beam test measurements are in progress
 - □ *Preliminary results show further performance improvements*





MIMOSA26 with high resistivity EPI layer (2)

Beam test at CERN SPS (120 GeV pions)

- <u>Test conditions:</u>
 - 50 MHz to emulate the longer integration time in ULTIMATE
 - 35 °C temperature!

